

Correction

# Correction: Wen et al. Fabrication of Dense Gadolinia-Doped Ceria Coatings via Very-Low-Pressure Plasma Spray and Plasma Spray–Physical Vapor Deposition Process. *Coatings* 2019, 9, 717

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The author wishes to make the following correction to this paper [1]. Due to mislabeling, replace:

**Table 2.** Parameters of the very-low-pressure plasma spray (VLPPS) and plasma spray–physical vapor deposition (PS-PVD).

Parameters	VLPPS Coating	PS-PVD Coating
Pressure (Pa)	150	150
Current (A)	720	2600
Torch	F4-VB	O3CP
Power (kW)	53	126
Plasma gas (Ar) (slpm) <sup>a</sup>	60	30
Plasma gas (He) (slpm) <sup>a</sup>	-	90
Plasma gas (H <sub>2</sub> ) (slpm) <sup>a</sup>	12	-
Powder feed rate (g·min <sup>-1</sup> )	2	10
Spraying distance (mm)	150	800
Substrate temperature (°C)	900–1000	800–900
Torch speed (mm/s)	300	500

with

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Plasma gas (H <sub>2</sub> ) (slpm) <sup>a</sup>	12	-
Powder feed rate (g·min <sup>-1</sup> )	2	10
Spraying distance (mm)	250	800
Substrate temperature (°C)	900–1000	800–900
Torch speed (mm/s)	300	500

The revised numbers are marked in red in the corrected table.

The authors would like to apologize for any inconvenience caused to the readers by these changes.

## Reference

1. Wen, J.; Song, C.; Liu, T.; Deng, Z.; Niu, S.; Zhang, Y.; Liu, L.; Liu, M. Fabrication of Dense Gadolinia-Doped Ceria Coatings via Very-Low-Pressure Plasma Spray and Plasma Spray–Physical Vapor Deposition Process. *Coatings* **2019**, *9*, 717. [[CrossRef](#)]



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